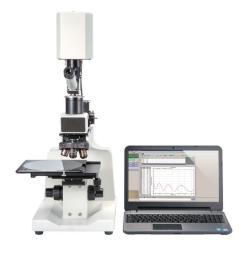


# TohoSpec 3100

## Film Thickness Measurement

The TohoSpec 3100 is a state of the art, small spot spectroscopic reflectometer, built on a simple-to-use tabletop platform. A reliable solid state linear diode array is used to ensure measurement speed and accuracy. Incorporating core technology acquired from market leader Nanometrics, this system is specifically designed for a wide variety of R&D applications. The TohoSpec 3100's Windows software interface is easy to use, and is supplied with a suite of measurement programs that handle most semiconductor films. The flexible software design makes it simple for the engineer to customize measurement programs and recipe jobs for more advanced applications. The TohoSpec 3100 delivers the same trusted results as its predecessors while offering the user enhanced versatility and data management.



### **Standard Features**

### **Comprehensive Measurements**

The 3100 provides scanning from 380nm to 800nm and can measure single layer films such as oxide, nitride, and photoresist, as well as multiple layer film stacks of up to three layers simultaneously. Measurements can also be made on a wide variety of other substrates including silicon, aluminum and gallium arsenide.

#### **Dynamic Software**

The 3100 software platform allows for the creation of unique single and multiple layer programs for proprietary films and film stacks utilized in modern semiconductor processes. With the ability to select film constants, scan ranges, and substrate types, the 3100 is the ideal tool for rapid measurement program development. Data management features, statistical analysis, histograms, and the ability to import and export data files are all standard.

### **Enhanced by W.Theiss SCOUT**

Powerful and flexible SCOUT software provides increased measurement capabilities including:

- Simultaneous measurement of optical constant (n, k)
- Simple and advanced dispersion models for optical material characterization:
  - Cauchy: Transparent film (SiO2, SiN, PI, Photo Resist etc.)
  - OJL model, Tauc-Lorentz: Interband transition models with 'built-in' Kramers-Kronig relation
  - Extended Drude model: Conductive film, ITO, TiN etc
- Optical models for film condition assessment:
  - EMA: Surface roughness and Interface roughness etc.
  - Graded: Nonhomogeneous in the direction of depth. Enhancement of the optical model for film condition.

# **Applications**

The TohoSpec 3100 is designed to provide accurate film thickness measurements across a vast array of applications.

- LED
- Solar
- FPD / LCD
- OLED
- Photomask
- Power Device
- SO
- Magnetic head for HDD

**Films:** All partially transparent films **Layers:** Guaranteed 3 layer measurement and in some cases beyond 3 depending on parameters

**Substrates:** Most smooth or semi-smooth surfaces with some reflectance

**Sample Info:** Sequence of the film stack, film materials, nominal thickness of each layer

#### Toho Technology Inc.

4809 N Ravenswood Ave, Suite 113 Chicago, Illinois 60640 Tel: 773.583.7183 www.tohotechnology.com



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### Film Thickness Measurement

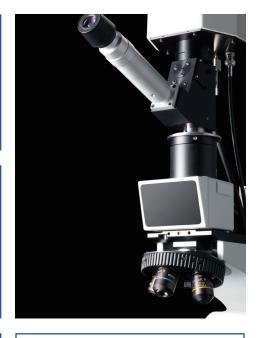
# **Highly Configurable**

With attention to versatility, the 3100 is highly configurable. Small spot size measurements can be performed with the 5x ( $\phi50\mu m$ ) standard lens. Higher precision measurements are possible with an optional 10x ( $\phi25\mu m$ ) and 50x ( $\phi5\mu m$ ) lens. With the 3100T model, film layers as thick as 70  $\mu m$  are measurable with an installed small-aperture system.

## **Streamlined Design for Ease of Use**

The TohoSpec 3100 has been refined to produce the same trusted results with less time consumption than older models.

- Users are able to hook up the tool to any desktop or laptop via Ethernet port
- Si chip is embedded on the stage for convenient reference measurement
- Smaller footprint (280 mm x 472 mm)
- 5x standard lens. Smaller spot size



# **Specifications**

#### **Performance**

Film Stack / Number of Films Wavelength Range

#### Film Thickness Range

Standard Configuration (5x)
Thick Film Configuration (5x)
Repeatability
Film Type / n & k values
Measurement Time

Data Management

#### **Hardware Configuration**

Wafer Sizes
Head Unit
Optics / Spot Sizes
5x (standard)
10x (optional)
50x (optional)
100x (optional for Thick film)

### **Optical Filters**

Yellow cutoff filter

Orange cutoff filter

Up to 3 layers simultaneously 380 - 800 nm (Standard) 380 - 850 nm (Thick film)

100 Å - 30 μm 100 Å - 70 μm 2 Å Obtained 0.1 to 2.5 seconds/site (3100) 0.01 to 2.5 second / site (3100 T) Statistical data analysis, Data export (ASCII)

Stage handles 3, 4, 5, 6, 8 inch wafers Reflectometer Linear Array

50 μm (15 μm for Thick film) 25 μm (7.5 μm for Thick film) 5 μm (1.5 μm for Thick film) (0.75 μm for Thick film)

480 nm (measured at 50% light transmission)
560 nm (measured at 50% light transmission)

### **Options**

- I0x objective
- 50x objective
- 100x objective 0.75 μm small spot
- Small aperture system for thick film measurement
- Color video camera with dedicated 17" flat panel display
- CD-RW drive
- Color printer
- Cleanroom operations manual (hard copy)
- NanoStandard film thickness standard wafer (6- or 8-inch)<sup>2</sup>

#### Notes

Film thickness range assumes oxide on silicon. Ranges for other films may vary.

<sup>2</sup>NanoStandard® wafers are NIST-traceable film thickness standards consisting of six pads of different oxide thicknesses on silicon.

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Specifications subject to change.